

STATEMENT OF WORK FORMAT

Thin Film Measurement System

Background

- The Detector Development Lab needs an extended wavelength range thin film measurement system for measuring the thickness of transparent thin films on semiconductor wafers
- This system will allow the measurement of silicon films. Current facilities are limited due to the limited wavelength range. This will be a general purpose instrument and will extend the capabilities for the lab as a whole and all projects will benefit from the added capability.
- No statutory authority or applicable regulations
- Provides copies of pertinent background materials, including them in a *Reference* or *Attachment*.

Scope

- The Contractor shall provide a Thin Film Measurement System with a minimum wavelength range of 380 nanometers (nm) to 1700 nm. In addition the system shall include a model for determining the thickness and porosity of Porous Silicon.

Requirements

- Describes detailed work and management requirements, including required meetings
- The Contractor shall provide a Thin Film Measurement System with a minimum wavelength range of 380 nanometers (nm) to 1700 nm. In addition the system shall include a model for determining the thickness and porosity of Porous Silicon. A Calibration Standard and a Microscopic System for viewing the area to be measured shall be included. Shipping charges shall be included in the procurement.
- Any necessary setup of the Thin Film Measurement System and training Shall be included. One year of technical support shall be included.

Deliverables or Delivery Schedule

- One Thin Film Measurement System with a minimum wavelength range of 380 nanometers (nm) to 1700 nm. In addition the system shall include a model for determining the thickness and porosity of Porous Silicon.
- A Calibration Standard
- A Microscopic System for viewing the area to be measured shall be included.
-
- Delivery shall be within four weeks ARO.
- An Electronic copy of the Operation Manual shall be provided. An additional copy on Clean-room paper is optional

Government-Furnished Equipment and Government-Furnished Information

- No Government-furnished equipment (GPE) and Government-furnished information (GFI)

Place of Performance

- The Thin Film Measurement shall be fabricated at the contractor's facilities and delivered to NASA/GSFC

Period of Performance

- The period of performance shall be within 4 weeks after receipt of order.